

Specifications 技术参数

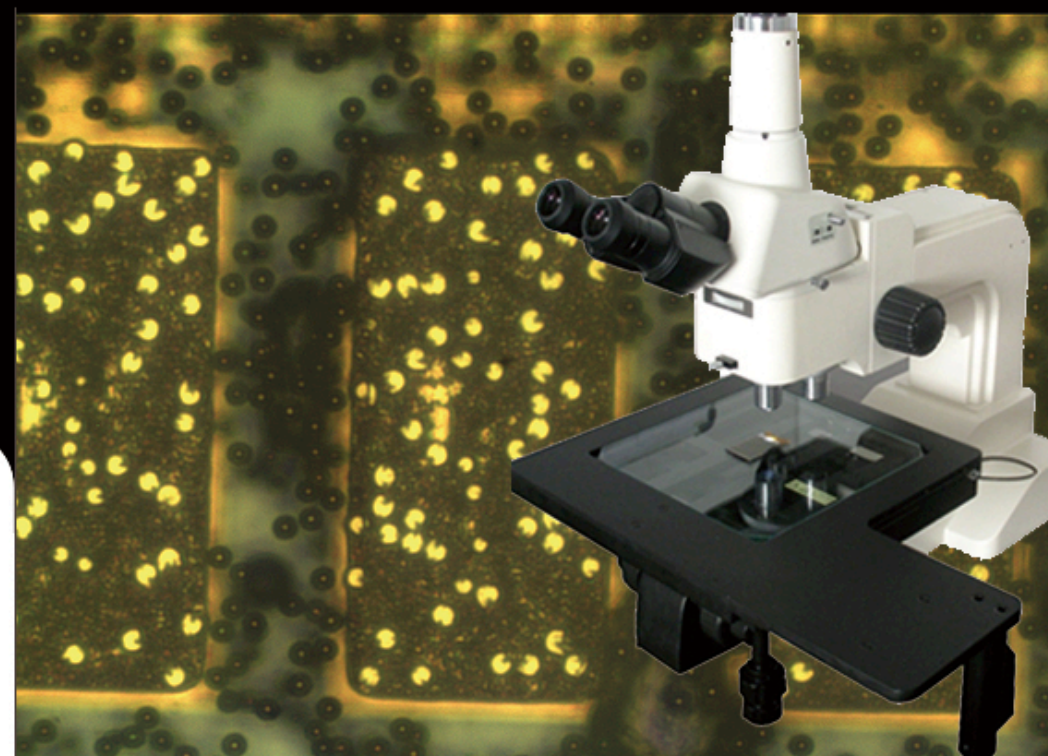
光学系统 Optical system		无限远光学系统 infinite optical system
物镜 Objectives		45mm/60mm/95mm系列 45mm/60mm/95mm series
目镜 Eyepieces		10X/Φ20mm、15X/Φ12mm
调焦装置 Focusing device	上调焦 Upper	粗调焦手轮：每旋转一周可升高或降低25毫米 coarse focusing handwheel: 25mm up/down per round
		垂直移动范围：从基准位置（焦面位置）向上/向下25毫米 vertical range: 25mm up/down from the standard position
	下调焦 Lower	微调焦手轮：每旋转一周可升高或降低载物台0.2毫米 fine focusing handwheel: 0.2mm up/down per round
		微调焦手轮刻度：2μm/每小格 fine focusing handwheel scale: 2μm/lattice
		垂直移动范围：基准位置（焦面位置）向上/向下7毫米 vertical range: 7mm up/down from the standard position
载物台 Stage	行程 Stroke	350mm(X) 255mm(Y)
转换器 Nosepiece		3孔平面转换器 three-hole plane nosepiece
输入电压 Voltage		110V-240V AC 2A
外形尺寸 Size		500(L) x 450(W) x 470(H)
重量 Weight		30kg



SQ200

微分干涉金相显微镜

DIC Metallograph Microscope



www.sharpscope.com

普西森精密仪器有限公司

Sharpscope Precision Industrial Co., Ltd.

Address: Room 2203, No 251-B, Heyan Road, Nanjing

Tel: 86-025-85959041

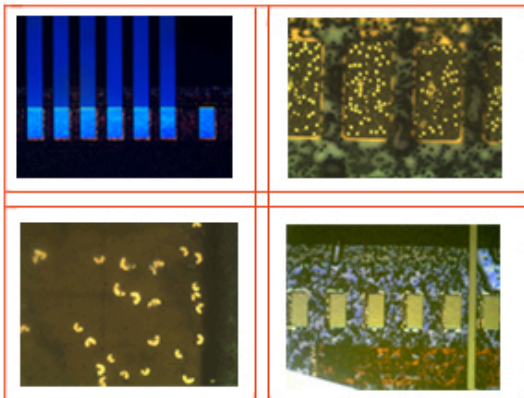
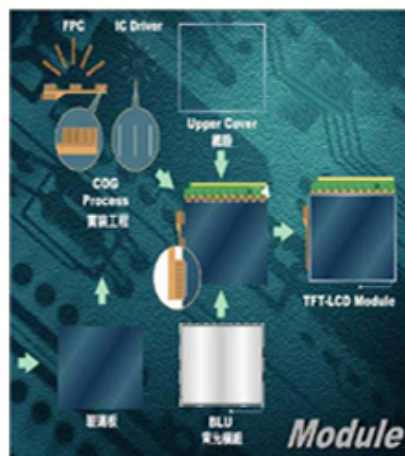
Fax: 86-025-85550455

Website: www.sharp-scope.com

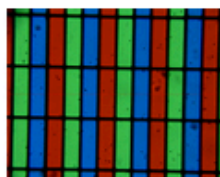
>>> 主要应用

SQ200微分干涉金相显微镜专业为LCD(OLCD)生产流程服务,在MODULE中对COG及ACF进行观察和检测。

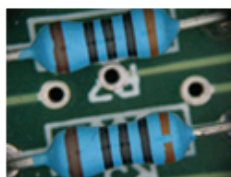
SQ200 DIC Metallograph Microscope serves IC(OLCD) production process professionally, it can also be used to observe, check and measure COG and ACF during MODULE.



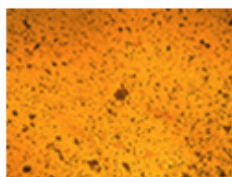
>>> 延伸应用



液晶



PCB



陶瓷



半导体

亦可广泛应用于材料分析、金相组织观测、半导体晶圆检测、PCB板检测等领域中。

It can also be widely used in fields such as material analysis, metallographic structure observation, semiconductor wafer and PCB observation.

>>> 产品特点



- 采用无限远光学系统,可适用各种无限远物镜,可配置45mm、60mm、95mm物镜
Based on the infinite optical system, applicable to various infinite objectives such as the 45/60/95mm series.
- 具备上下两套调焦系统,可观察较高较厚样品,上调焦行程为50mm,下调焦行程为14mm
Have the upper(stroke:50mm) and lower focusing systems (stroke: 14mm), is able to observe those high and thick samples.
- 配置8寸快速移动大平台,方便快捷
With the 8' fast stage, convenient and swift to operate.
- 配置偏振系统及微分干涉系统,可实现COG中粒子及爆破检测
Using the polarization and DIC system, can realize the detection of the particles in COG and blas
- 可配置落射照明和透射照明
Can be used with ultrapak and transmission illumination.
- 可加载晶圆旋转平台
Able to load the wafer rotation stage.

